

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Venkat Selvamanickam, et al.

Title: APPARATUS FOR AND METHOD OF CONTINUOUS HTS TAPE  
BUFFER LAYER DEPOSITION USING LARGE SCALE ION BEAM  
ASSISTED DEPOSITION

App. No.: 10/609,250 Filed: June 26, 2003

Examiner: Ram N. Kackar Group Art Unit: 1792

Customer No.: 34456 Confirmation No.: 7760

Atty. Dkt. No.: 1014-SP101-US

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MS AMENDMENT  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO NON-FINAL OFFICE ACTION**

Dear Sir:

In response to the Office Action mailed October 7, 2008, please amend the above-identified application as follows:

The Claim Amendments begin on page 2.

The Remarks begin on page 6.